

CNM Short Course A: Thin Film Deposition

Wednesday, May 5, Afternoon

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|-------------|--|
| 1:30 – 1:40 | Liliana Stan (Center for Nanoscale Materials, Argonne National Laboratory)
<i>Thin Films Characteristics and Deposition Methods</i> |
| 1:40 – 2:10 | Liliana Stan (Center for Nanoscale Materials, Argonne National Laboratory)
<i>Sputtering and Evaporation</i> |
| 2:10 – 2:20 | Break/Discussion |
| 2:20 – 3:00 | Liliana Stan (Center for Nanoscale Materials, Argonne National Laboratory)
<i>Atomic Layer Deposition (ALD)</i> |
| 3:00 – 3:20 | David Czaplewski (Center for Nanoscale Materials, Argonne National Laboratory)
<i>Chemical Vapor Deposition (CVD)</i> |
| 3:20 – 3:30 | Discussion |